

PROPOSED AMENDMENT ONLY

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FACSIMILE TRANSMISSION COVER SHEET

To: Examiner Bergin

Fax: (571) 273-6872

From: Azza M. JayaprakashYour Ref.: 10/585,356Our Ref.: 128528Number of Pages Sent (Including cover sheet): 6Prepared By: ldg**Comments:**Sent By: ldg

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Applicant Initiated Interview Request Form

Application No.: 10/585,356 First Named Applicant: Patrick BROYER
 Examiner: J. BERGIN Art Unit: 3641 Status of Application: First Office Action

Tentative Participants:

(1) Examiner BERGIN (2) A. JAYAPRAKASH (Reg. No. 55,299)
 (3) _____ (4) _____

Proposed Date of Interview: 2/25/09 Proposed Time: 10 AM (AM/PM)

Type of Interview Requested:

(1) Telephonic (2) Personal (3) Video Conference

Exhibit To Be Shown or Demonstrated: YES NO

If yes, provide brief description: _____

Issues To Be Discussed

Issues (Rej., Obj., etc)	Claims/ Fig. #s	Applied Reference(s)	Discussed	Agreed	Not Agreed
(1) <u>112 Rej.</u>	<u>1-15</u>	_____	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

Continuation Sheet Attached

Brief Description of Arguments to be Presented:

Thank you for agreeing to schedule a telephone interview regarding the above-identified application on Wednesday, February 25, 2009 at 10:00 a.m.

During the telephone interview, Applicants' representative intends to discuss the outstanding rejections under 35 U.S.C. § 112. In particular, Applicants wish to present the attached proposed amendments for the Examiner's consideration, in an effort to advance prosecution.

If you have any questions or comments, please do not hesitate to contact us.

An interview was conducted on the above-identified application on _____

NOTE:

This form should be completed by applicant and submitted to the examiner in advance of the interview (see MPEP § 713.01).

This application will not be delayed from issue because of applicant's failure to submit a written record of this interview. Therefore, applicant is advised to file a statement of substance of this interview (37 CFR 1.133(b) as soon as possible.


 (Applicant/Applicant's Representative Signature)

(Examiner/SPE Signature)

PROPOSED AMENDMENTS

1. (Currently Amended) A pyrotechnic microsystem comprising a substrate having at least two separate electrical initiation zones of a pyrotechnic material deposited on the substrate, ~~characterized in that~~ wherein the same pyrotechnic material deposit covers both initiation zones, said deposit ~~produced on the substrate~~ having a thickness sufficiently small for the initiation of the pyrotechnic material at one initiation zone to remain localized and not propagate to the other initiation zone, but sufficient to generate a specific gas quantity.

2. (Currently Amended) The microsystem as claimed in claim 1, wherein the pyrotechnic material deposit ~~is produced with~~has a thickness of less than 100 μm .

3. (Currently Amended) The microsystem as claimed in claim 1, wherein the substrate ~~is produced from~~comprises an assembly of superimposed layers.

4. (Previously Presented) The microsystem as claimed in claim 3, wherein the pyrotechnic material deposit constitutes one of the superimposed layers.

5. (Currently Amended) The microsystem as claimed in claim 4, wherein the pyrotechnic material deposit is ~~used as an adhesive for assembly~~ between a layer lying above said deposit and a layer lying below said deposit.

6. (Previously Presented) The microsystem as claimed in claim 1, wherein the deposited pyrotechnic material is in the form of a nitrocellulose-based varnish.

7. (Currently Amended) The microsystem as claimed in claim 6, wherein the varnish is deposited with has a thickness of between 5 and 40 μm after drying.

8. (Currently Amended) The microsystem as claimed in claim 1, wherein each of the initiation zones can be produced ~~from~~ initiated by an electrical resistance on the substrate.

9. (Currently Amended) The microsystem as claimed in claim 1, wherein each of the initiation zones can be produced at the point of contact of a conductive finger, connected to an electrical generator on the substrate, and wherein the substrate is made of metallic substance, which is also connected to said generator.

10. (Currently Amended) The microsystem as claimed in claim 3, comprising a deformable membrane partially delimiting a combustion chamber ~~intended to receive the~~ gases generated by at least one part of the pyrotechnic material deposit in contact with one of the initiation zones.

11. (Currently Amended) The microsystem as claimed in claim 10, comprising a layer through which an orifice forming the combustion chamber is formed, said layer being ~~held~~ between the membrane, itself forming a layer, and the pyrotechnic substance deposit.

12. (Currently Amended) A method for fabricating a microsystem comprising a plurality of adjacent microactuators established on a substrate, each microactuator being capable of having a specific effect owing to the gases generated by the combustion of a pyrotechnic material initiated from an electrical initiation zone associated with each microactuator, wherein comprising: depositing a pyrotechnic material layer common to all the

microactuators is deposited on the substrate with a thickness sufficiently small for the initiation of the pyrotechnic substance in one initiation zone to remain localized and not propagate to the other initiation zone, but sufficient to generate a specific gas quantity.

13. (Currently Amended) The method as claimed in claim 12, ~~wherein it consists only in consisting of~~ stacking superimposed layers, the pyrotechnic material layer constituting one of the layers of the stack.

14. (Previously Presented) The method as claimed in claim 12, wherein the pyrotechnic material layer is deposited with a thickness of less than 100 μm .

15. (Currently Amended) The method as claimed in claim 12, wherein the pyrotechnic material layer is deposited by coating, screen printing, pad printing, immersion or ~~by spraying~~.

16. (New) The microsystem as claimed in claim 1, comprising at least one microactuator on said substrate.

17. (New) The microsystem as claimed in claim 16, wherein said microactuator comprises a chamber covered by a deformable membrane.

18. (New) The microsystem as claimed in claim 16, comprising a plurality of microactuators on said substrate.

20. (New) A substrate for a pyrotechnic microsystem, comprising a sheet having at least two separate electrical initiation zones of a pyrotechnic material deposited on the sheet, wherein the same pyrotechnic material deposit covers both initiation zones, said deposit having a thickness sufficiently small for the initiation of the pyrotechnic material at

one initiation zone to remain localized and not propagate to the other initiation zone, but sufficient to generate a specific gas quantity.